



IECW

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kazuo ICHIKAWA et al.

Group Art Unit: 1763

Application No.: 09/670,877

Examiner: R. ZERVIGON

Filed: September 27, 2000

Docket No.: 107469

For: CVD SYSTEM AND Substrate Cleaning Method

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the March 17, 2006 Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**